

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2067		SERIAL NO. 10/624340 <small>Filed Herein</small>	
LIST OF ART CITED BY APPLICANT <small>(Use several sheets if necessary)</small>				APPLICANT Brant A. McClure et al			
				FILING DATE Filed Herewith		GROUP Unknown 2831	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Class	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
/NH/	AA	6,180,481	1/01	DeBoer et al			
	AB	6,218,256	4/01	Agarwal			
	AC	6,284,049	8/00	Solayappan			
	AD	6,180,447	1/01	Park			
	AE	6,274,428	8/01	Wu			
	AF	6,124,158	9/00	Dautartas et al			
	AG	6,144,060	11/00	Park			
	AH	5,316,982	5/94	Taniguchi			
	AI	6,281,142	8/99	Bascari et al			
	AJ	6,204,172	9/98	Marab			
↓	AK	5,432,732	7/95	Ohmi			
/NH/	AL	6,242,299	06/01	Hickert			

FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AO							

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)			
/NH/	AR		A.W. Olt, et al., "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pps. 128-136.
	AS		

EXAMINER /Nguyen Ha/	DATE CONSIDERED 06/20/2007
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.